

PALM INTRANET

Day : Monday
 Date: 2/3/2003
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Inventor Name Search Result

Your Search was:

Last Name = MEIKLE
 First Name = SCOTT G.

Application#	Patent#	Status	Date Filed	Title	Inventor Name
08386023	5698455	150	02/09/1995	METHOD FOR PREDICTING PROCESS CHARACTERISTICS OF POLYURETHANE PADS	MEIKLE , SCOTT G.
08643420	6239492	150	05/08/1996	SEMICONDUCTOR STUTURE WITH A TITANIUM ALUMINUM NITRIDE LAYER AND METHOD FOR FABRICATING SAME	MEIKLE , SCOTT G.
08904657	5989470	150	08/01/1997	METHOD FOR MAKING POLISHING PAD WITH ELONGATED MICROCOLUMNS	MEIKLE , SCOTT G.
08660849	5892281	150	06/10/1996	TANTALUM- ALUMINUM- NITROGEN MATERIAL FOR SEMICONDUCTOR DEVICES	MEIKLE , SCOTT G.
09201576	6206759	150	11/30/1998	POLISHING PADS AND PLANARIZING MACHINES FOR MECHANICAL OR CHEMICAL-MECHANICAL PLANARIZATION OF MICROELECTRONIC-DEVICE SUBSTRATE ASSEMBLIES, AND METHODS FOR MAKING AND USING SUCH PADS AND MACHINES	MEIKLE , SCOTT G.
09207058	6432818	150	12/07/1998	A METHOD OF USING TANTALUM- ALUMINUM-NITROGEN MATERIAL AS DIFFUSION BARRIER AND ADHESION LAYER IN SEMICONDUCTOR DEVICES	MEIKLE , SCOTT G.
08704328	5942449	150	08/28/1996	METHOD FOR REMOVING AN UPPER LAYER OF MATERIAL FROM A SEMICONDUCTOR WAFER	MEIKLE , SCOTT G.
08712949	Not Issued	161	09/13/1996	SEMICONDUCTOR WAFER POLISHER	MEIKLE , SCOTT G.
07828721	5231306	150	01/31/1992	TITANIUM/ALUMINUM/NITROGEN MATERIAL FOR SEMICONDUCTOR DEVICES	MEIKLE , SCOTT G.
07914748	5254499	150	07/14/1992	METHOD OF DEPOSITING HIGH DENSITY TITANIUM NITRIDE FILMS ON SEMICONDUCTOR WAFERS	MEIKLE , SCOTT G.
08723901	5795218	150	09/30/1996	POLISHING PAD WITH ELONGATED MICROCOLUMNS	MEIKLE , SCOTT G.
08728269	6395620	150	10/08/1996	METHOD FOR FORMING A PLANAR SURFACE OVER LOW DENSITY FIELD AREAS ON A SEMICONDUCTOR WAFER	MEIKLE , SCOTT G.
08078700	5341016	150	06/16/1993	LOW RESISTANCE DEVICE ELEMENT AND INTERCONNECTION STRUCTURE	MEIKLE , SCOTT G.
09289791	Not Issued	041	04/09/1999	PLANARIZING SOLUTIONS, PLANARIZING MACHINES AND METHODS FOR MECHANICAL OR CHEMICAL-MECHANICAL PLANARIZATION OF MICROELECTRONIC-DEVICE SUBSTRATE ASSEMBLIES	MEIKLE , SCOTT G.
08560734	5609718	150	11/20/1995	METHOD AND APPARATUS FOR MEASURING A CHANGE IN THE THICKNESS OF POLISHING PADS USED IN CHEMICAL-MECHANICAL PLANARIZATION OF SEMICONDUCTOR WAFERS	MEIKLE , SCOTT G.
08914994	6114706	150	08/20/1997	"METHOD & APPARATUS FOR PREDICTING PROCESS CHARACTERISTICS OF POLYURETHANE PADS"	MEIKLE , SCOTT G.
08247811	Not Issued	161	05/23/1994	LOW RESISTANCE DEVICE ELEMENT AND INTERCONNECTION STRUCTURE	MEIKLE , SCOTT G.
08526001	5795495	150	09/08/1995	METHOD OF CHEMICAL MECHANICAL POLISHING FOR DIELECTRIC LAYERS	MEIKLE , SCOTT G.
09324737	6290576	150	06/03/1999	SEMICONDUCTOR PROCESSORS,SENSORS, AND SEMICONDUCTOR PROCESSING SYSTEMS	MEIKLE , SCOTT G.
09189703	6206756	150	11/10/1998	TUNGSTEN CHEMICAL-MECHANICAL POLISHING PROCESS USING A FIXED ABRASIVE POLISHING PAD AND A TUNGSTEN LAYER CHEMICAL-MECHANICAL POLISHING SOLUTION SPECIFICALLY ADAPTED FOR CHEMICAL-MECHANICAL	MEIKLE , SCOTT G.

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				POLISHING WITH A FIXED ABRASIVE PAD	
09206511	6133636	150	12/07/1998	TANTALUM-ALUMINUM-NITROGEN MATERIAL FOR SEMICONDUCTOR DEVICES	MEIKLE , SCOTT G.
08535991	5655951	150	09/29/1995	METHOD FOR SELECTIVELY RECONDITIONING A POLISHING PAD USED IN CHEMICAL-MECHANICAL PLANARIZATION OF SEMICONDUCTOR WAFERS	MEIKLE , SCOTT G.
08812177	5801066	150	03/06/1997	METHOD AND APPARATUS FOR MEASURING A CHANGE IN THE THICKNESS OF POLISHING PADS USED IN CHEMICAL-MECHANICAL PLANARIZATION OF SEMICONDUCTOR WAFERS	MEIKLE , SCOTT G.
09382218	6426288	150	08/24/1999	METHOD FOR REMOVING AN UPPER LAYER OF MATERIAL FROM A SEMICONDUCTOR WAFER	MEIKLE , SCOTT G.
08049565	5377429	150	04/19/1993	METHOD AND APPARATUS FOR SUBLIMING PRECURSORS	MEIKLE , SCOTT G.
08588738	6040613	150	01/19/1996	ANTIREFLECTIVE COATING AND WIRING LINE STACK	MEIKLE , SCOTT G.
08862752	6331488	150	05/23/1997	PLANARIZATION PROCESS FOR SEMICONDUCTOR SUBSTRATES	MEIKLE , SCOTT G.
09388246	6168696	150	09/01/1999	NON-KNURLED INDUCTION COIL FOR IONIZED METAL DEPOSITION, SPUTTERING APPARATUS INCLUDING SAME, AND METHOD OF CONSTRUCTING THE APPARATUS	MEIKLE , SCOTT G.
09138793	6218295	150	08/24/1998	SEMICONDUCTOR STRUCTURE WITH A TITANIUM ALUMINUM NITRIDE LAYER AND METHOD FOR FABRICATING SAME	MEIKLE , SCOTT G.
09138811	6271590	150	08/21/1998	GRADED LAYER FOR USE IN SEMICONDUCTOR CIRCUITS AND METHOD FOR MAKING SAME	MEIKLE , SCOTT G.
09164915	6250994	150	10/01/1998	METHODS AND APPARATUSES FOR MECHANICAL AND CHEMICAL-MECHANICAL PLANARIZATION OF MICROELECTRONIC-DEVICE SUBSTRATE ASSEMBLIES ON PLANARIZING PADS	MEIKLE , SCOTT G.
09421165	6194308	150	10/19/1999	METHOD OF FORMING WIRE LINE	MEIKLE , SCOTT G.

Inventor Search Completed: No Records to Display.

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